

<b>Notice of References Cited</b>	Application/Control No. 10/671,381	Applicant(s)/Patent Under Reexamination MIRKIN ET AL.	
	Examiner William P. Fletcher III	Art Unit 1762	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
*	N	WO 99/56176 A1	11-1999	WIPO	Andreoli et al.	-----
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)			
*	U	Hong et al., "Multiple Ink Nanolithography: Toward a Multiple-Pen Nano-Plotter," Science, vol. 286, pp. 523-525, October 15, 1999.			
	V				
	W				
	X				

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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